Docket No. 0160-0193-0 PCT



## IN THE UNITED ST. PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF: Hiroshi IKEDA, ET AL.

GAU:

1754

SERIAL NO: 09/463,961

EXAMINER: VANOY, T.

FILED:

MAY 25, 2000

FOR:

METHOD AND APPARATUS FOR PROCESSING EXHAUST GAS OF SEMICONDUCTOR FABRICATION

## REQUEST FOR EXTENSION OF TIME UNDER 37 C.F.R. 1.136

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

## SIR:

It is hereby requested that a two month extension of time be granted to APRIL 21, 2002 for

- filing a response to the Final Rejection dated: NOVEMBER 21, 2001
- ☐ responding to the requirements in the Notice of Allowability dated:
- ☐ filing the Formal Drawings. The Issue Fee due

has been timely filed.

- ☐ responding to the Notice to File Missing Parts of Application dated:
- ☐ filing a Notice of Appeal. A timely response to the final rejection, due

has been filed.

- ☐ filing an Appeal Brief. A Notice of Appeal was filed on:
- ☐ Applicant claims small entity status. See 37 CFR 1.27. Therefore, the fee amount shown below is reduced by one-half.

The required fee of \$400.00 is enclosed herewith by check and any further charges may be made against the Attorney of Record's Deposit Account No. 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully Submitted,

OBLON, SPIVAK, McCLELLAND,

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